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0834-0243-0

IN RE APPLICATION OF

HIDEAKI SAKURAI ET AL : EXAMINER: JACKSON, MONIQUE R.

SERIAL NO: 09/457,743 :

FILED: DECEMBER 10, 1999 : GROUP ART UNIT: 1773

FOR: PROTECTIVE THIN FILM FOR :  
FPDS, METHOD FOR PRODUCING  
SAID THIN FILM AND FPDS USING  
SAID THIN FILM

AMENDMENT AND REQUEST FOR RECONSIDERATION

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Responsive to the Office Action of August 28, 2002, Applicants respectfully request reconsideration of the above-identified application in view of the following amendment and remarks.

IN THE SPECIFICATION

Please replace the paragraph on page 8, lines 1-7 with the following paragraph.

*B*  
In accordance with the present invention, as shown in Figs. 1 and 2, a FPD protecting film comprises a film body 14a formed on a substrate 13 and made of any one of MgO, CaO, SrO, BaO, alkali earth compound oxides, rare earth oxides, and compound oxides of alkali earth oxides and rare earth oxides; and a fluoride layer 14b formed on the surface of the film body 14a.

Please replace the paragraph on page 8, lines 8-16 with the following paragraph.